

Methods and Systems for Processing a Bevel Edge of a Substrate Using a Dynamic Liquid Meniscus

ABSTRACT OF THE DISCLOSURE

A system and method for processing an edge of a substrate includes an edge roller and a first proximity head. The first proximity head being mounted on the edge roller. The first proximity head capable of forming a meniscus and including a concave portion and multiple ports opening into the concave portion. The concave portion being capable of receiving an edge of a substrate and the ports including at least one process liquid injection port, at least one vacuum port and at least one surface tension control port.